

CLAIMS

What is claimed is:

- 1 1. An apparatus for remotely monitoring and developing steps in a semiconductor
2 manufacturing process comprising:
3 at least one remote workstation connected via a remote access link to a local
4 workstation;
5 a test system connected via a link to the local workstation.
- 1 2. The apparatus of claim 1, further comprising a client switch that connects a client
2 network to at least one remote workstation.
- 1 3. The apparatus of claim 1, further comprising a host switch that connects a host
2 network to the test system and when engaged, prevents client access to the test system.
- 1 4. The apparatus of claim 3, wherein the host switch comprises a manual switch.
- 1 5. The apparatus of claim 3, wherein the host switch comprises an ethernet switch.
- 1 6. The apparatus of claim 3, wherein the host switch comprises computer security
2 software.
- 1 7. The apparatus of claim 1, wherein the remote access link comprises:
2 a wide area network communication line operatively coupling the local
3 workstation to the remote workstation.
- 1 8. The apparatus of claim 7, wherein the remote access link further comprises at
2 least one router.

1 17. The apparatus of claim 14, wherein at least one of the remote access links
2 comprises a dedicated WAN technology.

1 18. The apparatus of claim 14, further comprising a host switch adapted to selectively
2 connect a host networking service to the test system.

1 19. The apparatus of claim 14, wherein the test system further comprises ancillary
2 equipment pre-selected by a client to test various functions of a semiconductor device.

1 20. The apparatus of claim 19, wherein the ancillary equipment further comprises a
2 temperature forcing unit.

1 21. The apparatus of claim 19, wherein the ancillary equipment further comprises a
2 wafer prober.

1 22. The apparatus of claim 19, wherein the ancillary equipment further comprises a
2 device handler.

1 23. A method for remotely monitoring and developing steps in semiconductor
2 manufacturing comprising:

3 running a semiconductor test system remotely from a remote workstation coupled
4 over a link to a local workstation, the local workstation being operatively coupled to the
5 test system;

6 monitoring the semiconductor test system remotely from the remote workstation;

7 and

8 receiving data from the semiconductor test system at the remote workstation.

1 24. The method of claim 23, wherein the semiconductor test system comprises a
2 semiconductor probe system for integrated circuit design debug and repair.

1 25. The method of claim 23, wherein the semiconductor test system comprises a test
2 system adapted to monitor the functionality of semiconductors produced by a fabrication
3 plant.

1 26. An apparatus for remotely monitoring and developing steps in a semiconductor
2 manufacturing process comprising:

3 at least one remote workstation operatively connected via a Wide Area Network
4 communication line to a local workstation;

5 a test system connected via a Local Area Network to the local workstation; and

6 a host network detachably connected by a host switch and a link to the test
7 system.

1 27. The apparatus of claim 26, further comprising a video camera networked to the
2 test system.